Response under 37 C.F.R. § 1.116

Expedited Procedure

Examining Group 1763

PATENT

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

5 In re application of:

Robert A. SHEPHERD JR et al.

Application No: 10/006,100

10

20

25

Filed: December 3, 2001

For:

METHOD AND APPARATUS

FOR PLASMA OPTIMIZATION

15 IN WAFER PROCESSING

Docket No: NOVEP015

Group Art Unit: 1763

Examiner: Zervigon, Rudy

Date: October 27, 2003

teclwish PC/8
12/31/03

CERTIFICATE OF MAILING

I hereby certify that this correspondence is being deposited with the United States Postal Service as First Class Mail to: Mail Stop AF, Commissioner of Patents, P.O. Box 1450, Alexandria, VA 22313-1450

on October 27, 2003.

Signed:

red: Feb Cabrasawan

RESPONSE TO FINAL OFFICE ACTION

30 Mai Stop AF

Commissioner for Patents
P.O. Box 1450

Alexandria, VA 22313-1450

Dear Sir:

This Amendment is in response to a FINAL Office Action dated August 27, 2003.

Please enter the following remarks.

Remarks begin on page 2.

40 .

35